

**IGNITION CONDITIONS FOR PERIPHERAL PLASMA  
IN A GROUNDED CHAMBER CONNECTED TO  
A DUAL FREQUENCY CAPACITIVE DISCHARGE**

**M.A. Lieberman**

**Department of Electrical Engineering and Computer Sciences  
University of California  
Berkeley, CA 94720**

## OUR GROUP

Prof. A.J. Lichtenberg — theory and modeling

Prof. J. Verboncoeur — dual/tri frequency PIC simulations

Prof. J.T. Gudmundsson (U. Iceland, visiting) — global modeling and experiments

Dr. Emi Kawamura — PIC simulations of heating

Sangsup Jeong (Samsung, visiting) — experiments and modeling

Sungjin Kim — global modeling and experiments

Alan Wu — PIC simulations of heating and ion energies

Acknowledgements:

Lam Research Corporation

National Science Foundation

UC Discovery/MICRO Programs

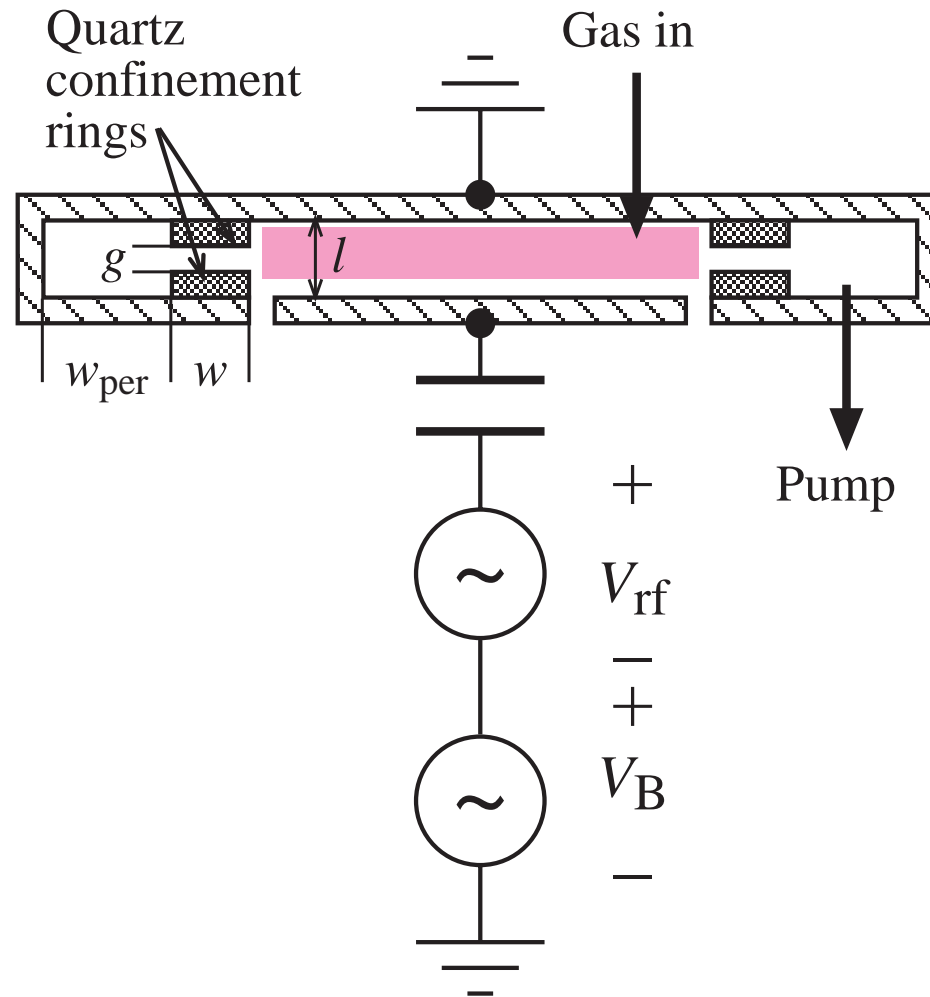
Thanks to: Doug Keil, Eric Hudson, and Reza Sadjadi

# OUTLINE OF TALK

- Introduction
- Discharge confinement
  - Plasma diffusion into slot (completed)
  - Plasma maintenance in slot and periphery (main topic)
  - Berkeley experiment (in progress)

# INTRODUCTION

# PLASMA CONFINEMENT BY DIELECTRIC RINGS



ConfinedPhys26Jul04

# DUAL FREQUENCY CAPACITIVE DISCHARGES

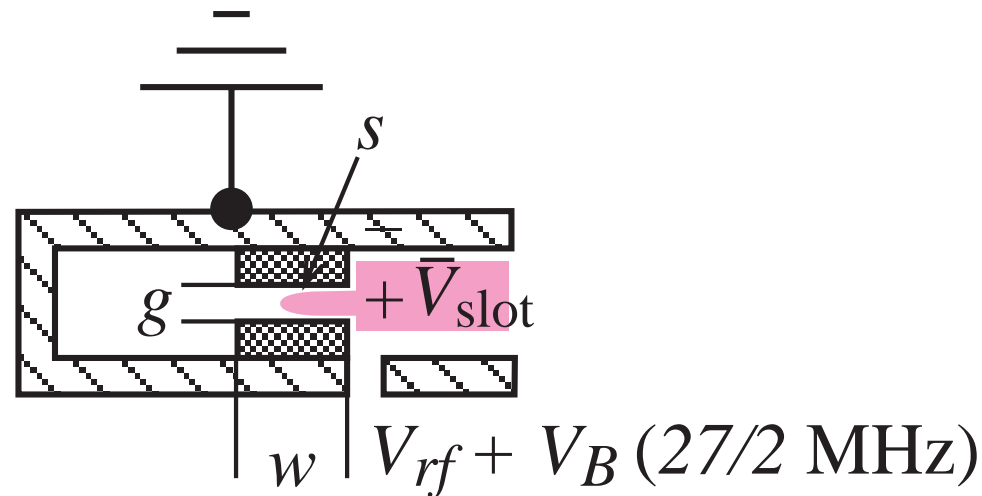
- $R \sim 15\text{--}30$  cm,  $l \sim 1\text{--}3$  cm
- $p \sim 30\text{--}300$  mTorr,  $\text{C}_4\text{F}_8/\text{O}_2/\text{Ar}$  feedstock
- High frequency  $f_{\text{rf}} \sim 27.1\text{--}160$  MHz,  $V_{\text{rf}} \sim 100\text{--}1000$  V
- Low frequency  $f_B \sim 2\text{--}13.56$  MHz,  $V_B \sim 500\text{--}3000$  V
- Absorbed powers  $P_{\text{rf}}$ ,  $P_B \sim 500\text{--}3000$  W
  
- For independent control of ion flux and energy

$$\frac{\omega_{\text{rf}}^2}{\omega_B^2} \gg \frac{V_B}{V_{\text{rf}}} \gg 1$$

(M.A. Lieberman, Jisoo Kim, J-P Booth, J-M Rax and M.M. Turner,  
SEMICON Korea Etching Symposium, p. 23, 2003)

# PLASMA TRANSPORT THROUGH SLOT

## BASIC DIFFUSION MODEL



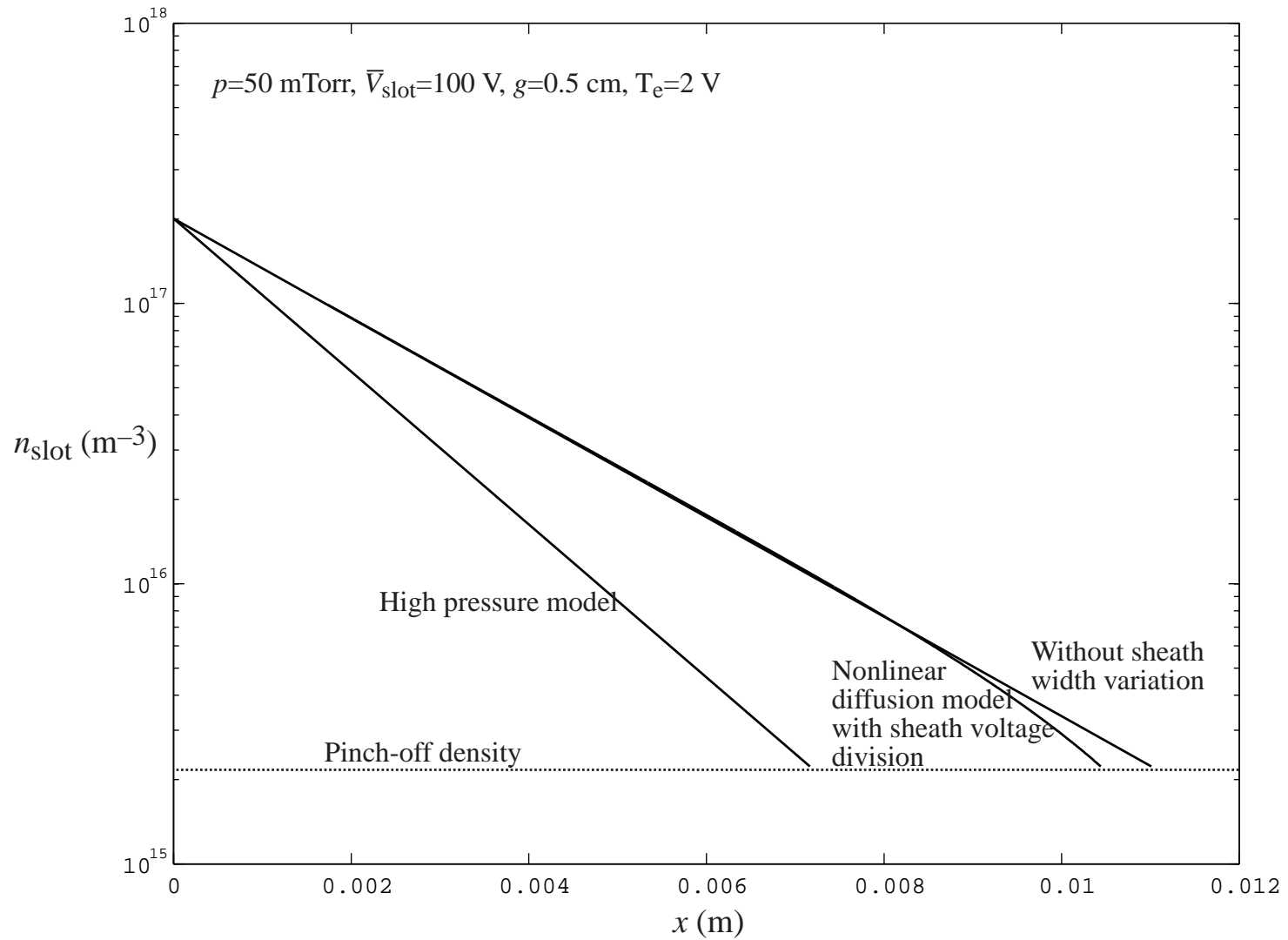
- $V_{\text{rf}} \Rightarrow$  plasma density  $n_0$  at slot entrance  
 $n_{\text{slot}}$  decays as plasma diffuses into slot
- $V_B + V_{\text{rf}} \Rightarrow$  dc plasma potential  $\bar{V}_{\text{slot}}$  within slot
- Child law  $\Rightarrow$  sheath width  $s$  within slot
- As  $n_{\text{slot}}$  decays,  $s$  increases until  $s = g/2 \Rightarrow$  plasma “pinch-off”
- Pinch-off length  $x_{\text{po}} \sim 0.5\text{--}1$  cm for 0.5 cm gap  $g$

## IMPROVEMENTS TO MODEL

- The sheath and the quartz ring form a capacitive voltage divider for the slot voltage  
⇒ reduced sheath voltage and modest increase in pinch-off length
- Low pressure diffusion model in slot for  $\lambda_i \gtrsim (T_i/T_e)g$   
⇒ modest increase in pinch-off length
- Sheath width varies with position within the slot  
⇒ slightly reduced pinch-off length
- Finite ionization rate within the slot  
⇒ modest increase in pinch-off length
- Collisional (not collisionless) Child law sheath in the slot  
⇒ slightly increased pinch-off length

# MODEL RESULTS

(collisionless sheath without ionization in slot)



## PINCH-OFF LENGTH

- A good estimate of the pinch-off length is

$$x_{\text{po}} \sim \frac{2g}{\pi} \ln \left( 0.12 \frac{g^2}{\lambda_{\text{D0}}^2} \frac{T_e^{3/2}}{\bar{V}_{\text{slot}}^{3/2}} \right)$$

where  $\lambda_{\text{D0}} = (\epsilon_0 T_e / en_o)^{1/2} =$  Debye length at slot entrance

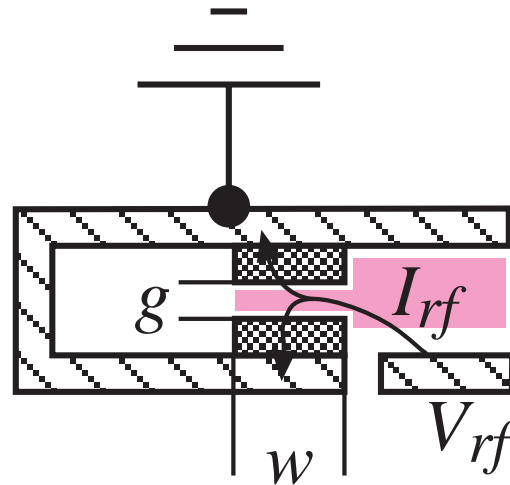
- There is a weak pressure dependence at high pressures
- For typical plasma parameters

$$x_{\text{po}} \sim 2g < \text{slot width } w$$

$\Rightarrow$  plasma does not diffuse through slot into periphery

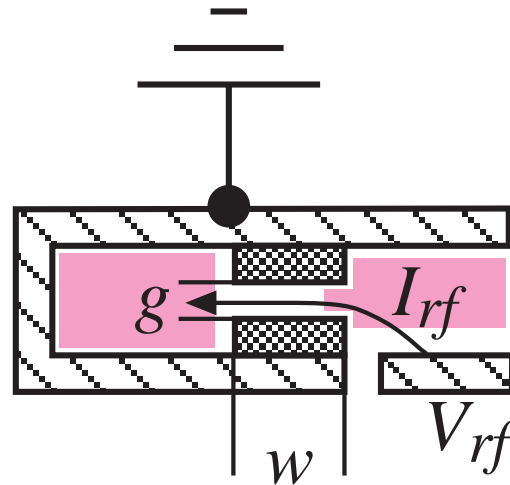
# DISCHARGE MAINTENANCE IN SLOT AND PERIPHERY

# DISCHARGE IN SLOT



- What are conditions for discharge maintained in slot?  
(“Maintenance curve”)
- “Breakdown” in slot not an issue with main discharge present
- Discharge in slot  $\implies$  discharge in periphery

## DISCHARGE IN PERIPHERY



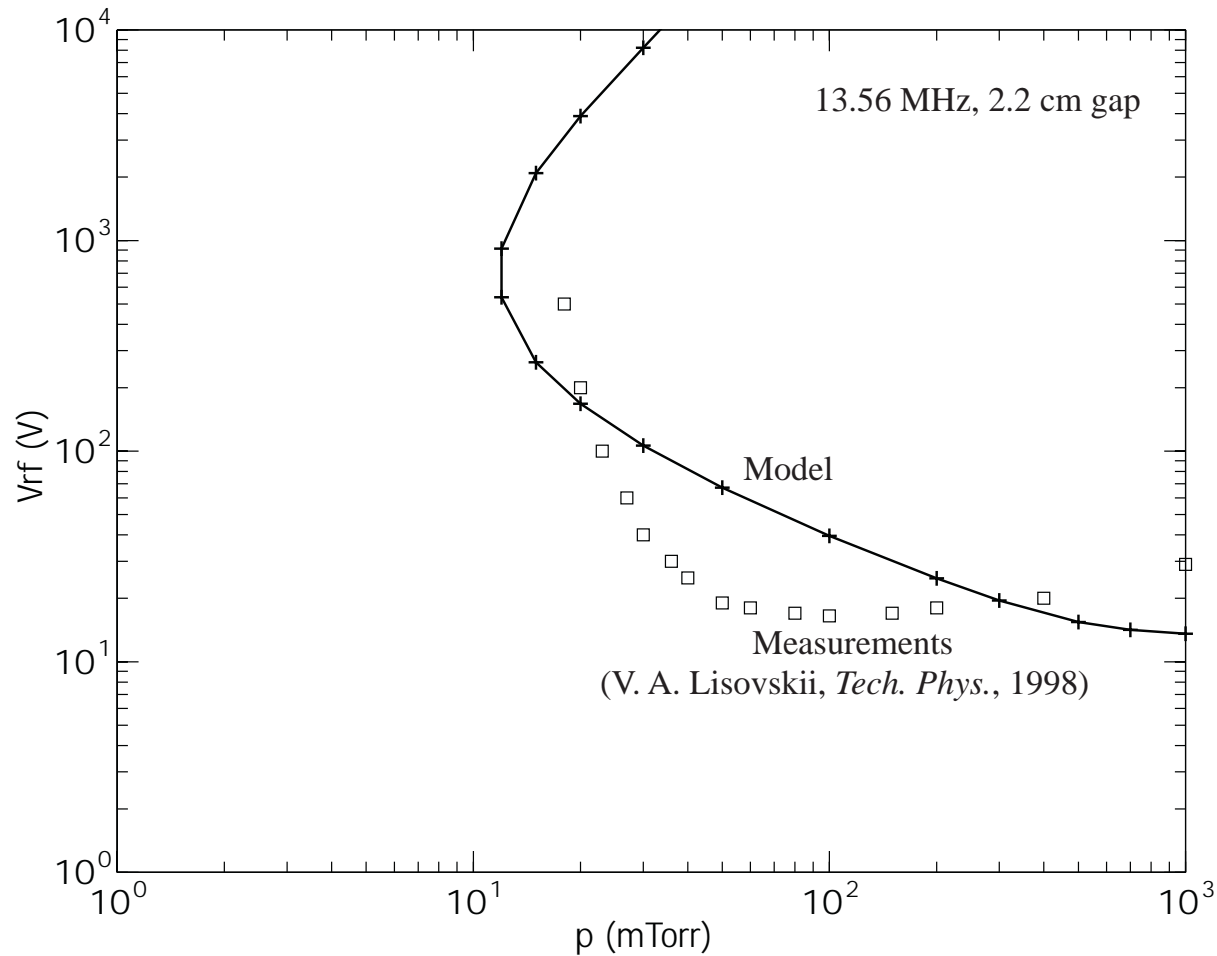
- For no discharge in slot, what are conditions for discharge maintained in periphery?
- “Breakdown” of periphery (as opposed to maintenance) may be an issue (to be investigated)
- Discharge in periphery  $\not\Rightarrow$  discharge in slot

# 1D MODEL OF DISCHARGE MAINTENANCE

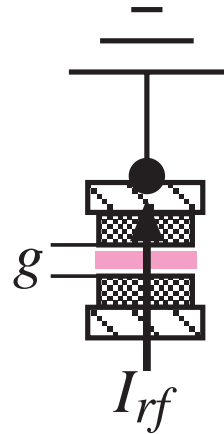
- Basic physics:
  - At low voltages (densities), total width of sheaths approaches gap spacing  $\Rightarrow$  bulk plasma becomes too thin
  - Ionization balance or power balance is lost
- Global model with additional physics at low rf voltages:
  - Account for a dc/low frequency sheath width in the absence of a high frequency sheath (Godyak/Sternberg, 1990)
  - Account for high frequency voltage drops across the dc/low frequency sheaths and the bulk plasma
  - Account for transition from ambipolar to free diffusion as bulk plasma becomes thin (Allis/Rose 1954)

# BENCHMARK 1D MODEL AGAINST MEASUREMENTS

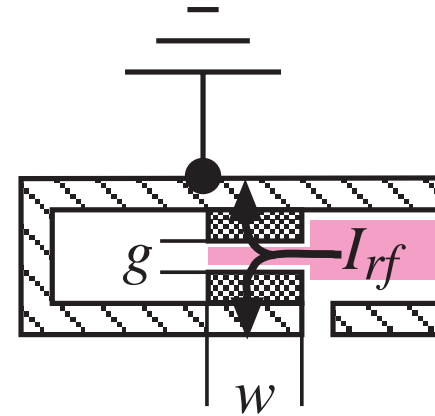
- Conventional capacitive discharge (argon)



## 2D RF CURRENT FLOWS IN SLOT



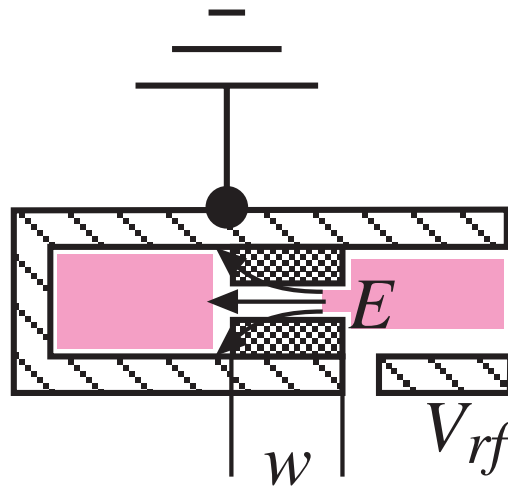
Conventional  
rf discharge



Slot discharge

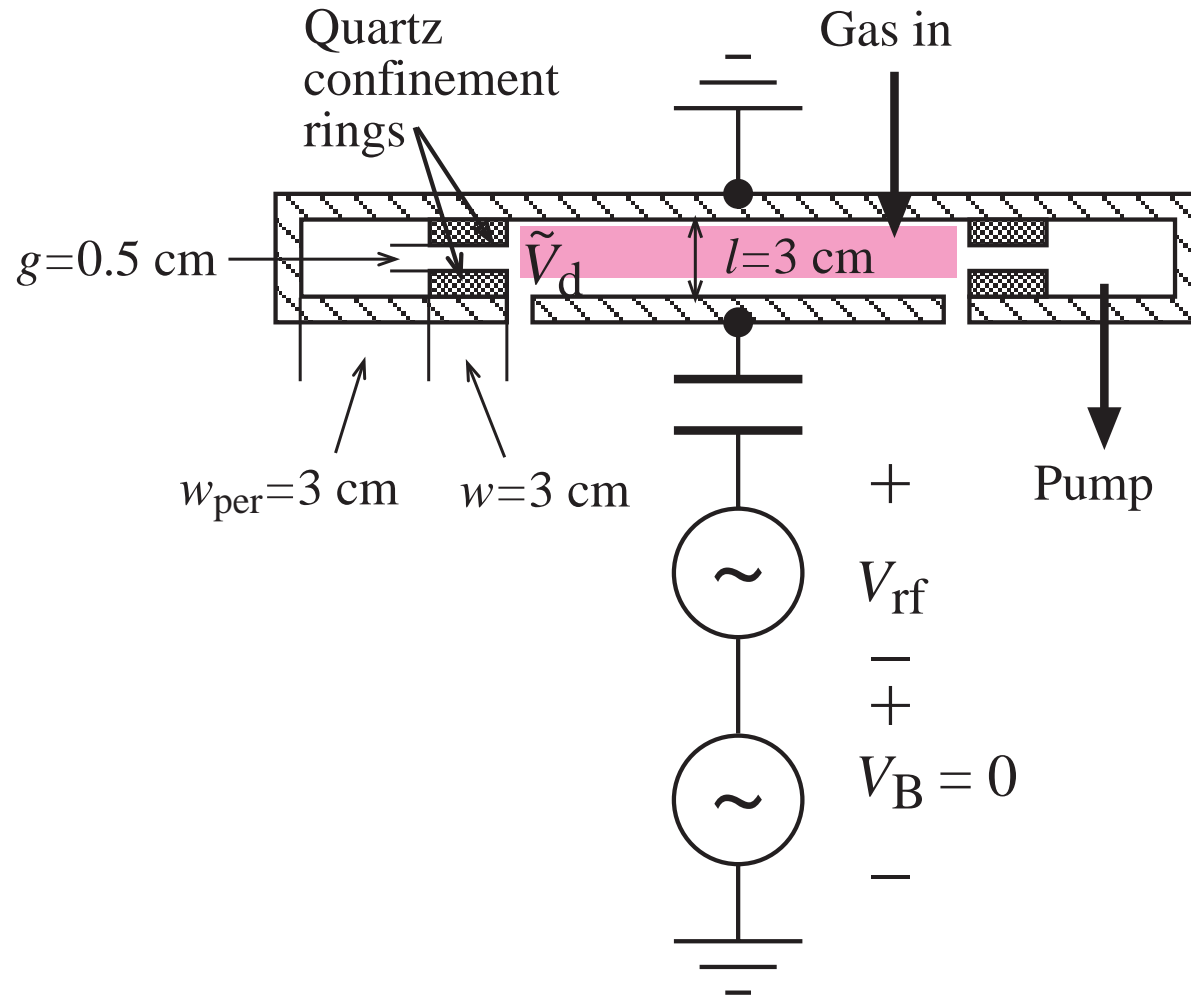
- Standard 1D global model has rf current transverse to plates
- Symmetric excitation of discharge in slot has 2D currents  
⇒ enhanced ohmic heating, incorporated into model
- When periphery ignites, current drawn through slot increases  
⇒ incorporated into model

## 2D CAPACITIVE COUPLING ACROSS SLOT



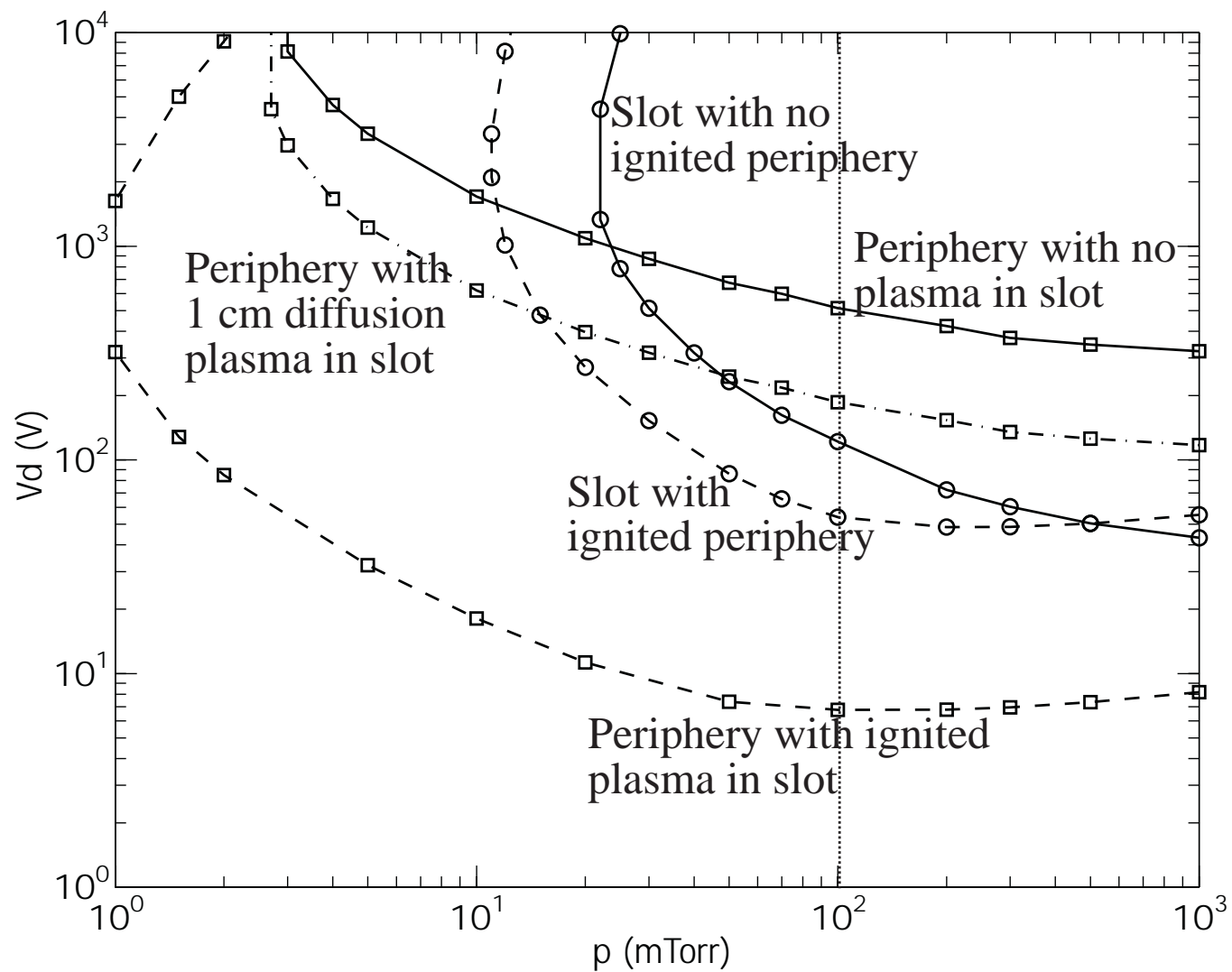
- Solve for decay of electric field  $E$  in dielectric region
- Decay depends on pinch-off length  
⇒ incorporated into model

# NOMINAL PARAMETERS



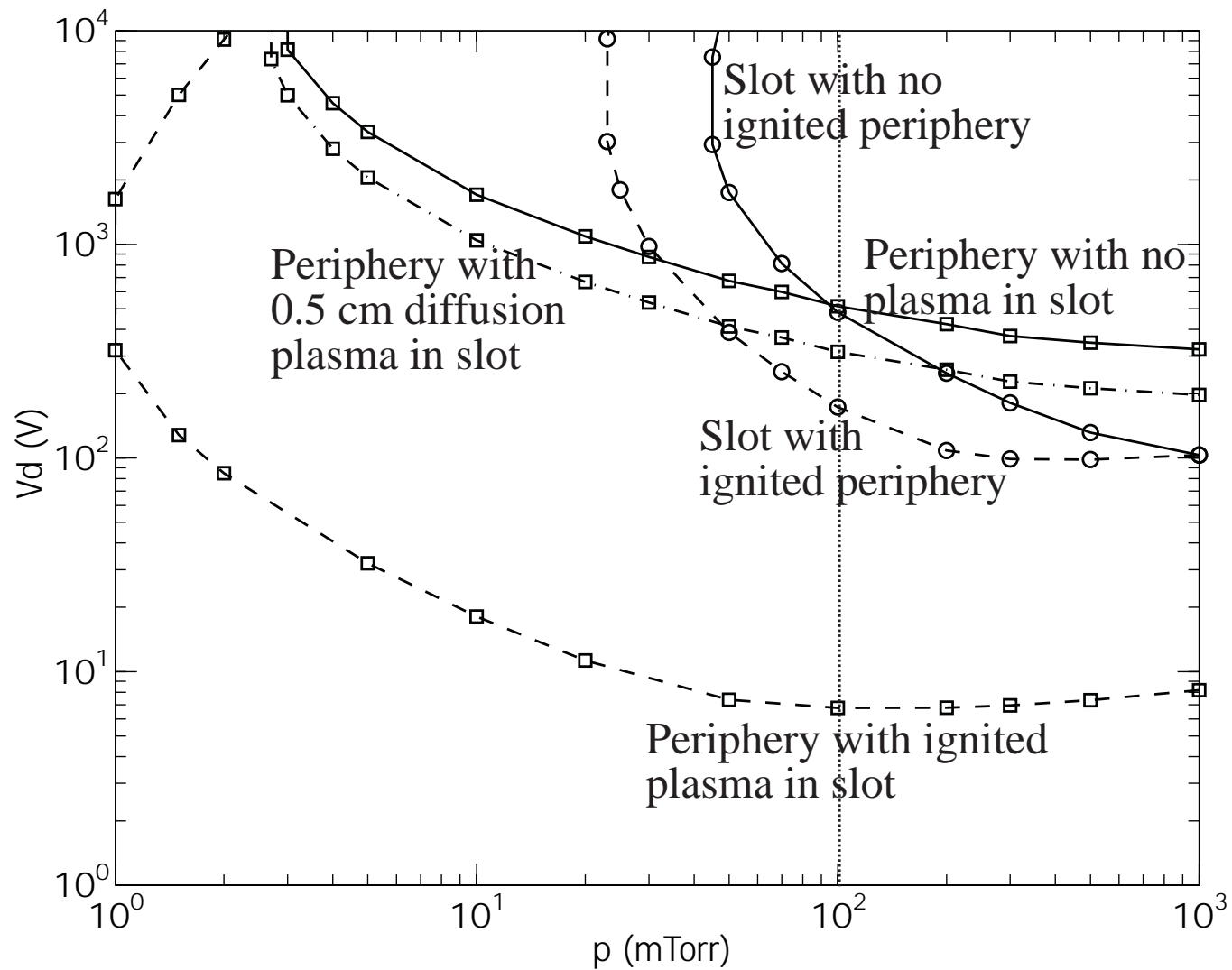
- Plot  $\tilde{V}_d$  versus pressure for maintenance in slot and periphery

# MAINTENANCE FOR NOMINAL PARAMETERS



- At 100 mTorr, slot ignites, then periphery ignites

## HALVE GAP SIZE TO 0.25 CM



- Now at 100 mTorr, periphery ignites, then slot ignites

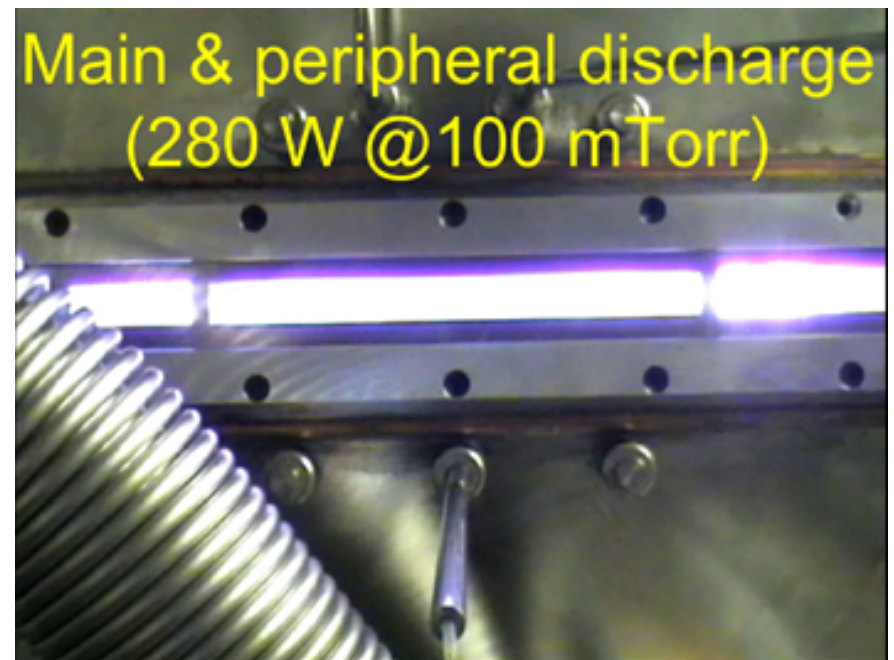
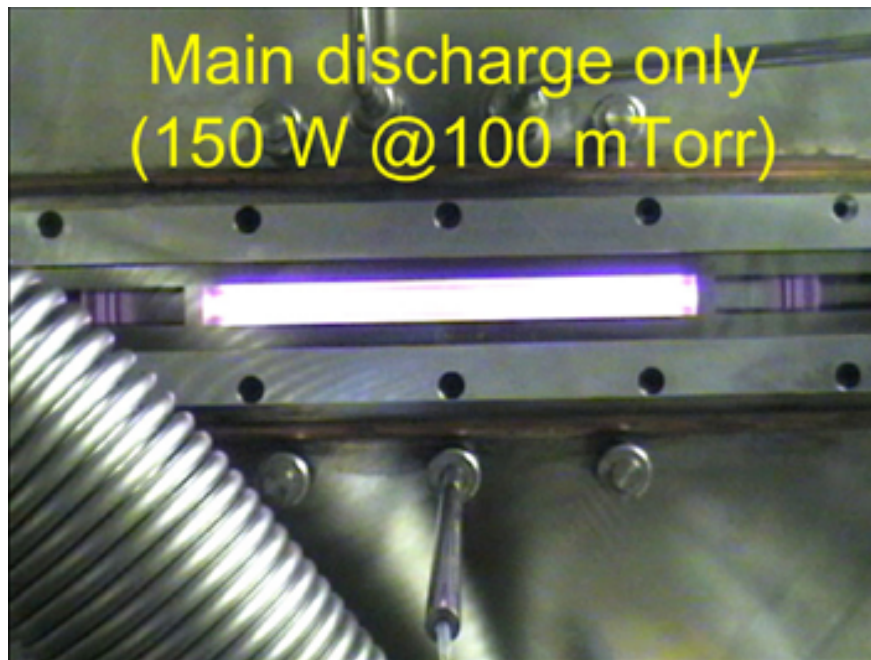
# BERKELEY EXPERIMENT

Sungjin Kim  
J.T. Gudmundsson  
Sangsup Jeong

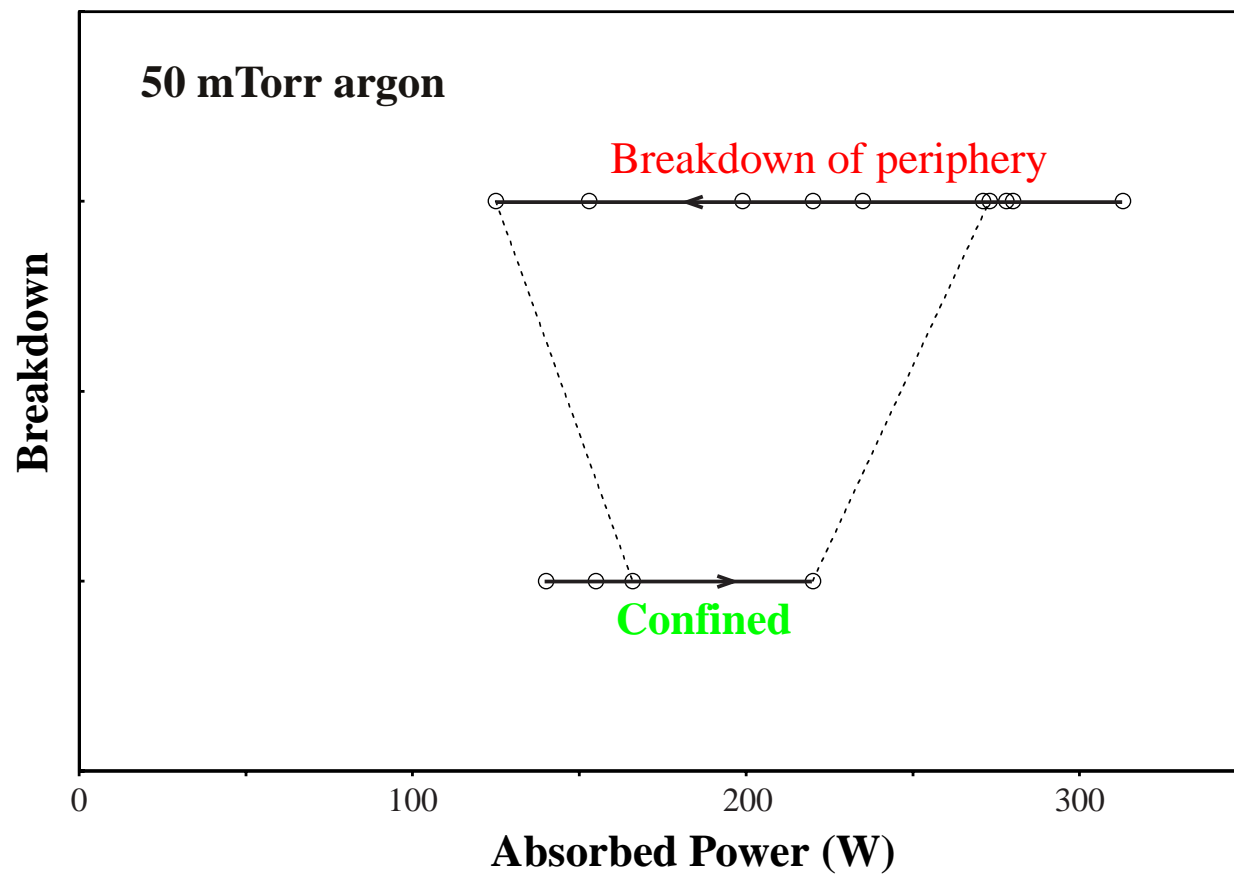
# CONFINED AND UNCONFINED PLASMA

- 27 MHz, 5 '' diameter powered electrode, 1/4'' slot gap  $g$

(View through window along a diameter of the grounded electrode)

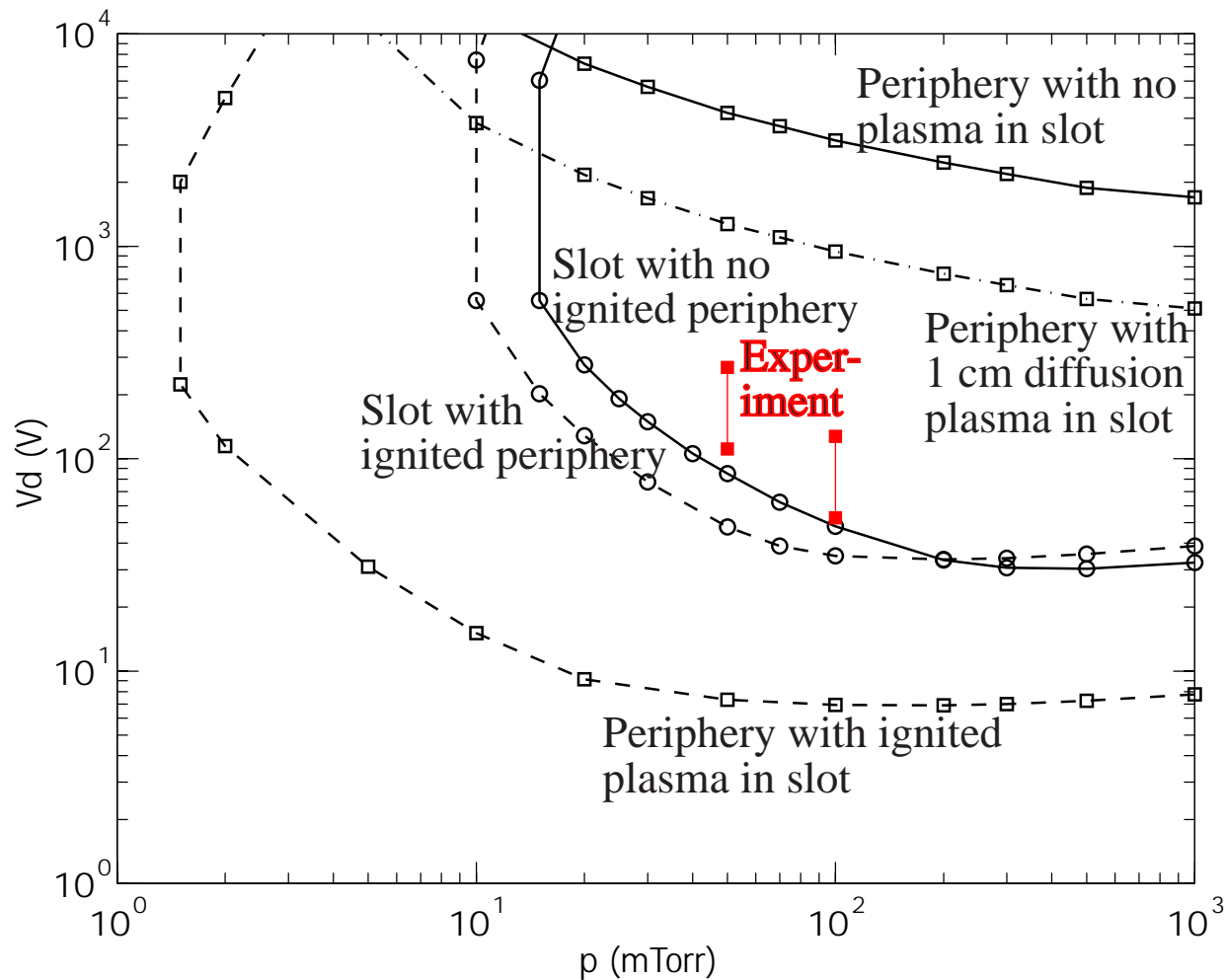


# HYSTERESIS IN POWER CHARACTERISTICS



# MAINTENANCE IN BERKELEY EXPERIMENT

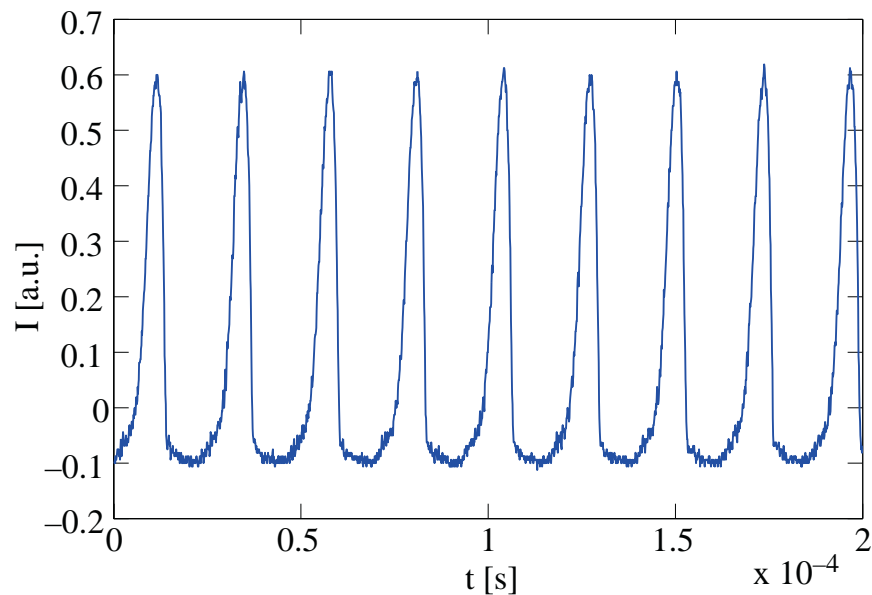
- $l = 2.54$  cm,  $g = 0.635$  cm,  $w = 3.8$  cm,  $w_{\text{per}} = 5.1$  cm



# INSTABILITIES WITH PERIPHERAL PLASMA

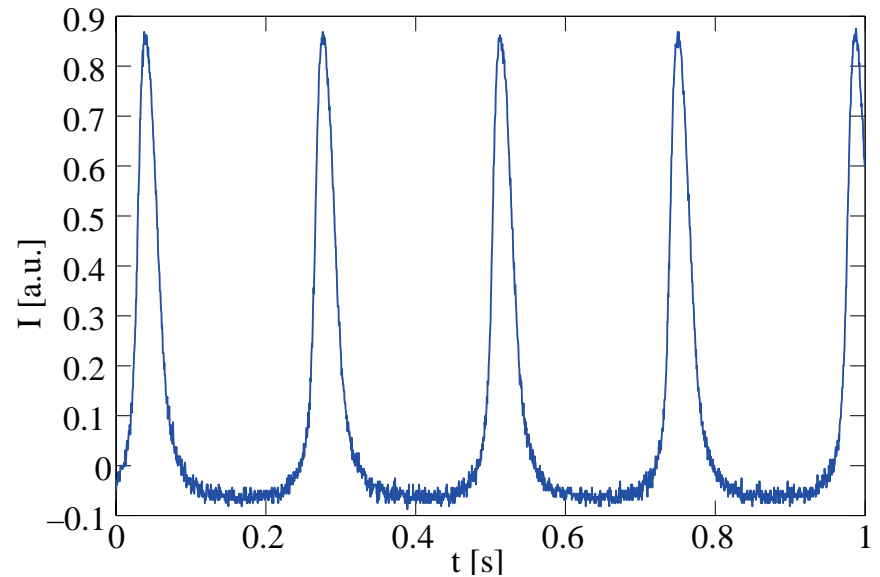
- 748.7 nm argon optical emission line in main discharge  
(the zero of  $I$  is not calibrated)

80 W, 100 mTorr



High frequency (43.3 kHz)  
relaxation oscillation

202 W, 77 mTorr



Low frequency (4.2 Hz)  
relaxation oscillation

## FUTURE PLANS

- Measure the rf voltage on main discharge plasma
- Experimentally characterize single frequency ignition (27 MHz) as a function of voltage, pressure, and gap spacing
- Experimentally characterize dual frequency ignition (27/2 MHz)
- Experimentally characterize instabilities and develop theoretical model
- Model effect of aspect-ratio of periphery on maintenance
- Model the effect of transport of electrons past pinch-off on peripheral ignition
- Model “breakdown” of periphery for no plasma in slot